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Substitution for Form 1449A/P10 INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete if Known	
				Application Number	10/760,025
				Filing Date	January 16, 2004
				First Named Inventor	Khalil Najafi, et al.
				Group Art Unit	
				Examiner Name	
Sheet	1	of	4	Attorney Docket Number	UOM 0289 PUSP

U.S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

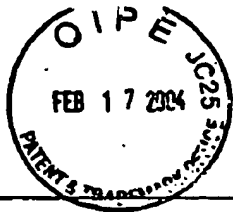
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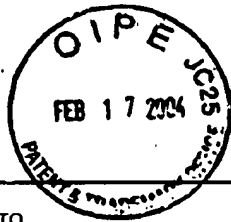


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OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials ¹	Cite No. ²	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ³
KZ		YAZDI, NAVID, ET AL., Micromachined Inertial Sensors, Proceedings of the IEEE, Vol. 86, No. 8, August 1998, pps. 1640-1659	
KZ		YAZDI, NAVID, Micro-g Silicon Accelerometers with High Performance CMOS Interface Circuitry, EECS, 1999, The University of Michigan, Ann Arbor, Michigan	
KZ		Analog-Devices, ADXL50, Monolithic Accelerometer with Signal Conditioning, Data Sheet, 1996, pps. 1-15	
KZ		Analog Devices, ADXL105, High Accuracy +-1g to +-5g Single Axis Imems Accelerometer with Analog Input, 1999, pps. 1-8	
KZ		LU, C., ET AL., A Monolithic Surface Micromachined Accelerometer with Digital Output, IEEE Journal of Solid-State Circuits, Vol. 30, No. 12, December 1995, pps. 1367-1373	
KZ		BOSER, BERNHARD E., ET AL., Surface Micromachined Accelerometers, IEEE Journal of Solid-State Circuits, Vol. 31, No. 3, March 3, 1996, pps. 366-375	
KZ		CROSS-BOW, High Sensitivity Accelerometer, LF Series Data Sheet, San Jose, California, 2001	
KZ		LUO, HAO, ET AL., A 1 mG Lateral CMOS-MEMS Accelerometer, 13 th IEEE International Conference on Micro Electro Mechanical Systems, MEMS 2000, Miyazaki, Japan	
KZ		WU, JIANGFENG, ET AL., A Low-Noise Low-Offset Chopper-Stabilized Capacitive-Readout Amplifier for CMOS MEMS Accelerometers, IEEE International Solid State Circuits Conference ISSCC 2002, San Francisco, California	
KZ		LEMKIN, M., ET AL., A Low-Noise Digital Accelerometer Using Integrated SOI-MEMS Technology, 10 th International Conference Solid-State Sensors And Actuators, Transducers 1999, Sendai, Japan	
KZ		ISHIHARA, KEI, ET AL., An Inertial Sensor Technology Using DRIE and Wafer Bonding with Interconnecting Capability, Journal of Microelectromechanical Systems, Vol. 8, No. 4, December 1999, pps. 403-408	

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KZ		GRIFFIN, W.S., ET AL., A Study of Fluid Squeeze-Film Damping, ASME Journal of Basic Engineering, June 1996, pps. 451-456	
KZ		ZHANG, XIA, ET AL., Viscous Air Damping In Laterally Driven Microresonators, Proceedings of The IEEE Micro Electro Mechanical Systems, 1994, pps. 199-204	
KZ		HENRION, WIDGE, ET AL., Wide Dynamic Range Direct Digital Accelerometer, Wide Dynamic Range Direct Digital Accelerometer, Solid State Sensors and Actuators Workshop, Hilton Head Island, SC, 1990	
KZ		YAZDI, NAVID, ET AL., All-Silicon Single-Wafer Micro-g Accelerometer with a Combined Surface and Bulk Micromachining Process, Journal of Microelectromechanical Systems, Vol. 9, No. 4, December 4, 2000, pps. 544-550	
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KZ		MAXWELL, PETER ET AL., Design Through to Production of a MEMS digital Accelerometer for Seismic Acquisition, First Break, Vol. 19, March 3, 2001	
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KZ		CHAE, JUNSEOK, ET AL., A Hybrid Silicon-On-Glass (SOG) Lateral Micro-Accelerometer With CMOS Readout Circuitry, 15 th IEEE International Conference on Micro Electro Mechanical Systems, MEMS 2002, Las Vegas, Nevada,	
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KZ		DOSCHER, JAMES, ADXL105: a Lower Noise, Wider Bandwidth Accelerometer Rivals Performance of More Expensive Sensors, 1999 Analog Dialogue 33-6, 1999 Analog Devices	

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HK		HONEYWELL, ASA7000, Micromachined Accelerometer, Data Sheet, July 2001 MOTOROLA, MMA2201D, Surface Mount Micromachined Accelerometer, Data Sheet 2000, pps. 1-8			
HK		ROYLANCE, L.M., ET AL., A Batch Fabricated Silicon Accelerometer, IEEE Trans Electron Devices, Vol. ED-26, No. 12, December 1979, pps. 1911-1917			
HK		SALIAN, A., ET AL., A High-Performance Hybrid CMOS Microaccelerometer, Solid-State Sensors and Actuators Workshop, Hilton Head Island, SC, June 4-8, 2000, pps. 285-288			
HK		ROARK, R.J., ET AL., Roark's Formulas for Stress and Strain, 6 th Ed. 1989, New York: McGraw-Hill, xiv, Vol. 763			
HK		WARREN, KEITH, Navigation Grade Silicon Accelerometers with Sarificially Etched SIMOX and BESOI Structure, Solid-State Sensors and Actuators Workshop, June 13-16, 1994 Hilton Head Island, SC, pps. 69-72			
HK		ENDEVCO, Variable Capacitance Accelerometer, Model 7596, Data Sheet, 2000			
HK		CHAE, JUNSEOK, ET AL., A Monolithic Three-Axis Silicon Capacitive Accelerometer With Micro-G Resolution, 12 th IEEE International Conference on Solid-State Sensors, Actuators and Microsystems, Transducers 2003, Boston, MA			

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